NANOFABRICATION LABORATORY

LAB OVERVIEW

Electronic and Photonic devices are serving as the key components in the field of carbon emission reduction, energy efficiency, electro-mobility, information technology, renewable energy, smart electricity distribution, wearable technology, and IoTenabled sensing in health and agriculture. The establishment of the Nanofabrication Lab at the Department of Electrical and Electronic Engineering, BUET, is going to play a significant role in research and development in the field of electronic and photonic nanodevice and nanosystem fabrication and characterization. This lab will have the capabilities for the fabrication of full-scale optoelectronic, electronic, photonic, bioelectronic, biophotonic, and electromechanical devices. This lab will act as a hub for the academic and industrial research communities by providing services, training, and access to research facilities for nanoscale fabrication. Developing costeffective and ingenious solutions for solving technological and engineering challenges of national importance will be the primary focus of the lab to attain SDGs and Smart Bangladesh Vision 2041.







Lab Directors

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PRIMARY RESEARCH AREA

- Nanoelectronics: Semiconductor devices with enhanced performance and reduced power consumption; Quantum bits (qubits) for quantum computers; Flexible and wearable electronic devices using nanoscale materials
- Nanophotonics: Nanoscale LEDs, lasers, and photodetectors; plasmonics for sensing and imaging; Optical communication systems.
- Nanomaterials: Nanowires and nanoparticles; Nanocomposites; Metamaterials
- Nanobiotechnology: Biosensors; Drug delivery systems; Tissue engineering; Diagnostic devices
- Energy Applications: Photovoltaics; Batteries and Supercapacitors, Fuel Cells
- Nanomechanics: NEMS; Molecular Machines
- Environmental Nanotechnology: Pollution remediation; Sustainable materials development
- Advanced Fabrication Techniques: 3D nanoprinting; Self-assembly











MISSION OF THE LAB

1. Innovative Research on Electronic and Photonic Nanomaterials:

To conduct extensive research on different electronic and photonic materials and devices for different applications through fabrication.

2. Nanodevice Fabrication:

To run different semiconductor front-end processes to fabricate the most optimized nanoscale device for suitable applications.

3. Educational Excellence and Training:

To provide comprehensive hands-on experience and training in micro and nanotechnologies, preparing students and researchers for leadership roles in the field of semiconductor materials and devices.

4. Prototyping and Production:

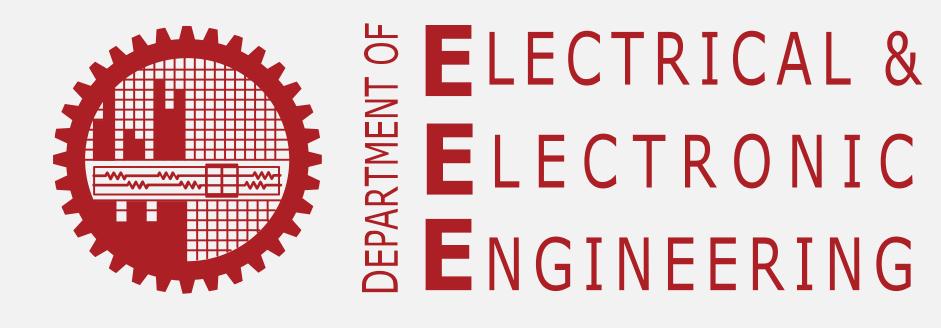
To turn research concepts into functional prototypes and to fabricate limited quantities of specialized nanodevices.

5. Interdisciplinary Collaboration:

To foster interdisciplinary collaboration and engage with the different institutes and research centers through workshops and outreach programs, promoting significance and understanding of nanotechnology.

FACILITIES AND EQUIPMENT

- Cleanroom (ISO6-Class 1000) 2000 sft
- o PICOMASTER200 (Mask less Laser Beam Lithography)
- E-beam-AJA ATC-1800-E (Metal and dielectric evaporator)
- Sputter-AJA-LL ATC-2200-UHV (Sputter deposition tool)
- Cambridge Nanotech Savannah 200 (Atomic Layer Deposition)
- PlasmaPro 100 Nano CVD (Growth of 1D/2D nanomaterials and heterostructures)
- o Air Control Custom Hotplate Tower (Hotplate tower for pre- and post-baking)
- CEE Apogee Spin Coater (Spinner for user-supplied resist and small samples)
- Yield Engineering YES-310TA (Photo / Bake)
- Thierry Diener Nano-QL-PCCE7 (Photo / Clean)
- Air Control FH-25-SS-6FT (Solvent fume hood for spin coating)
- Acid-Etch-General (Acid hood for general-purpose acid work)
- o SAMCO RIE-200iP (Chlorine-based plasma etcher for III-V materials)
- \circ RIE-mixed-Samco-230iP (Broad purpose ICP etcher with F_2 , Cl_2 , Br_2 Chemistry)
- RTA-1300C-ASOne150-5Gas ((Rapid Thermal Annealing))
- Diesaw-DAD3240 (Wafer dicing saw)
- KLS 10/12 (Chamber furnace working temperature up to 1200°C)
- o Nitrogen Gas Generator (Nitrogen gas supply to desiccators, gloveboxes)
- Negative Pressure & Vacuum Glove Boxes



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